

THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Peter CHOI
Title: PLASMA SOURCE OF DIRECTED BEAMS AND APPLICATION THEREOF TO MICROLITHOGRAPHY
Based Upon: PCT/FR2004/002656
Express Mail No. EV842850291US
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FIRST PRELIMINARY AMENDMENT

Mail Stop PCT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Please amend the subject U.S. Patent Application as follows to place this U.S. Patent Application in better condition for examination.

In the claims, substitute the following Claims 1-30 (Currently Amended) for the pending Claims 1-30 (Original).